

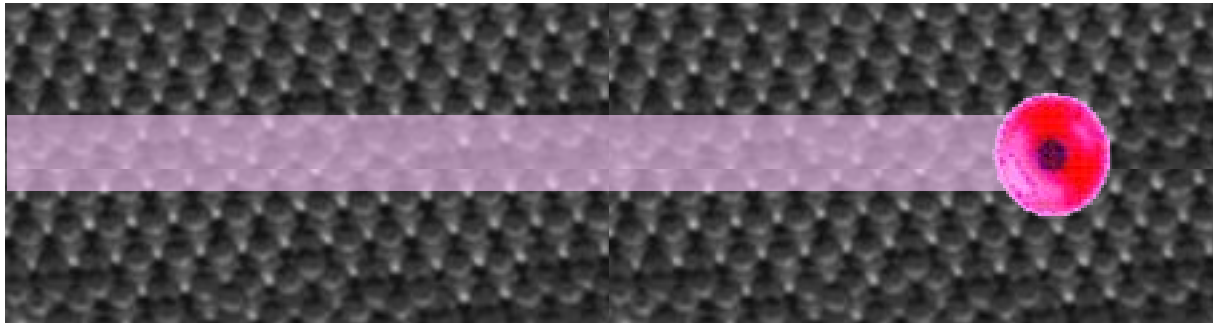
Energy loss along ion trajectory

1000-MeV Xe

$v = 10\% c$

range $\sim 50 \mu\text{m}$

flight time $\sim 10^{-12}$ s



energy loss (keV/nm)

high velocity
electronic dE/dx

low velocity
nuclear dE/dx

ions stop

range

$50 \mu\text{m}$



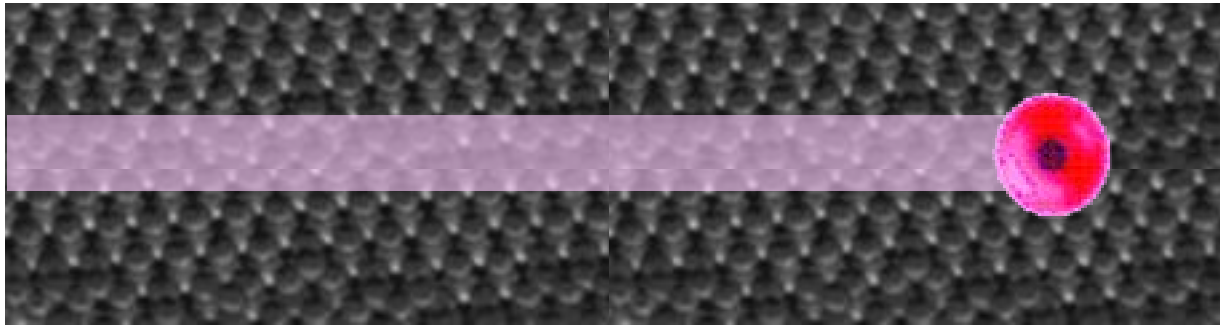
Ion - solid interaction

1-GeV Xe ion

$v = 10\% c$

range $\sim 50 \mu\text{m}$

flight time $\sim 10^{-12}$ s



49 μm

collisions with electrons
excitation and ionization



1 μm

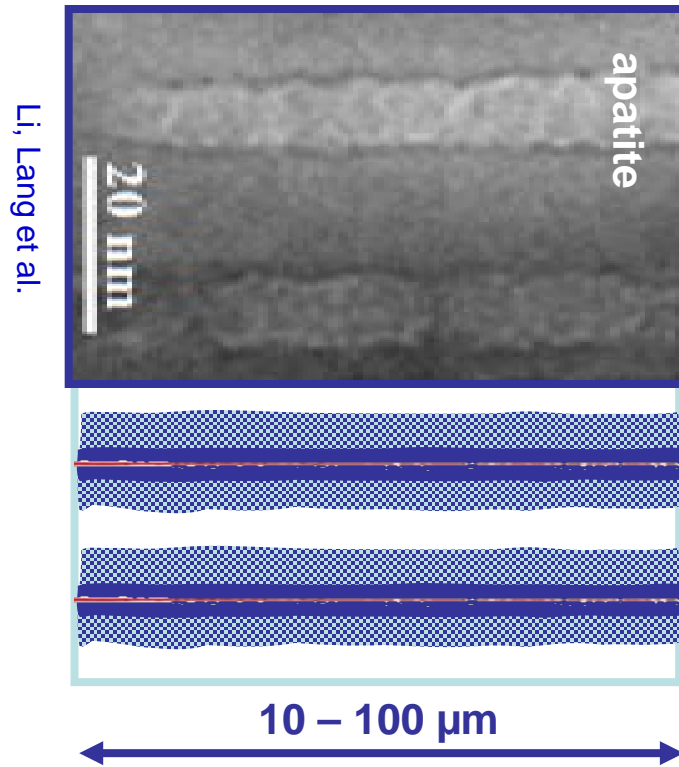
elastic collisions
with atoms



electron cascade

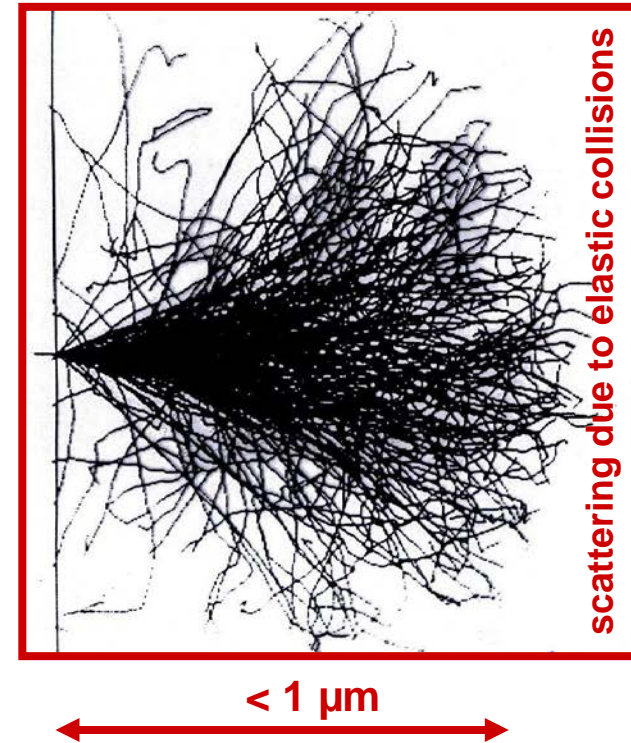


high energies (MeV-GeV)



- minimal scattering \rightarrow parallel tracks
- each ion produces cylindrical track
- track size scales with dE/dx
- track formation depends on material

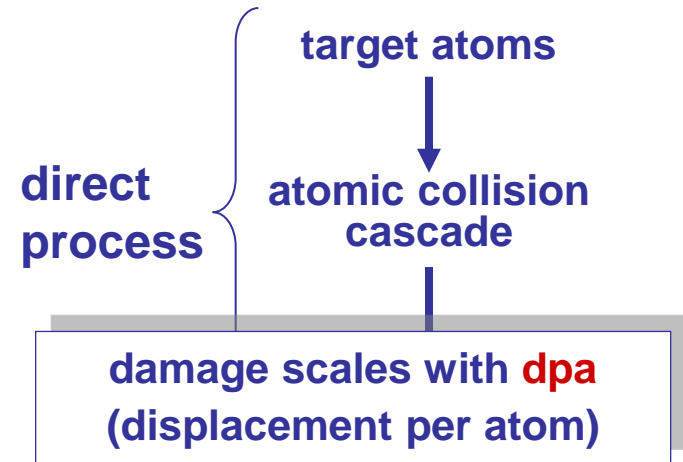
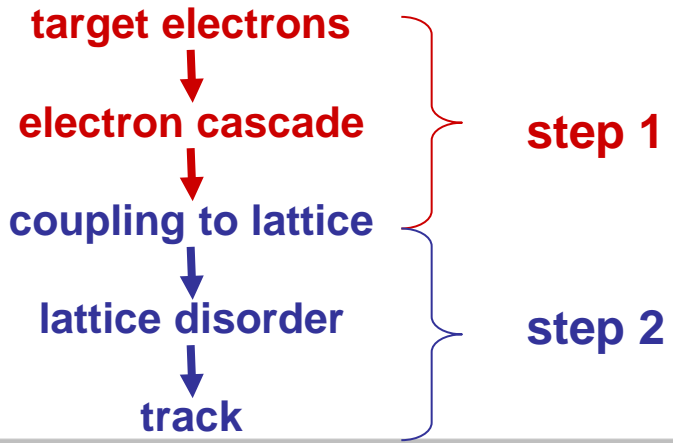
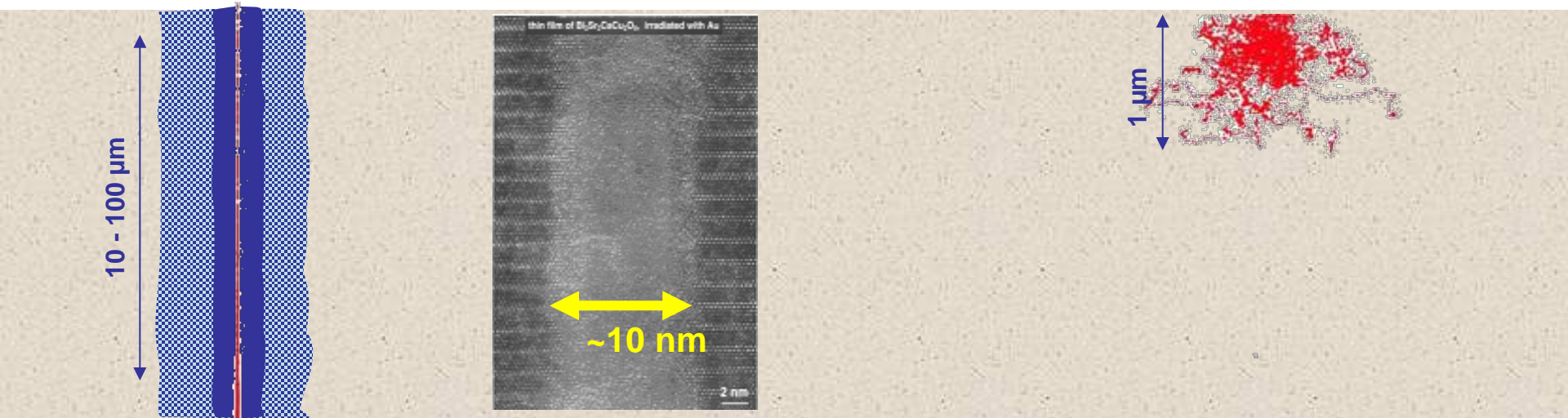
low energies (keV)



- elastic collision cascade (energy & momentum conservation)
- weak materials dependence
- important parameter \rightarrow displacement energy E_d

electronic stopping

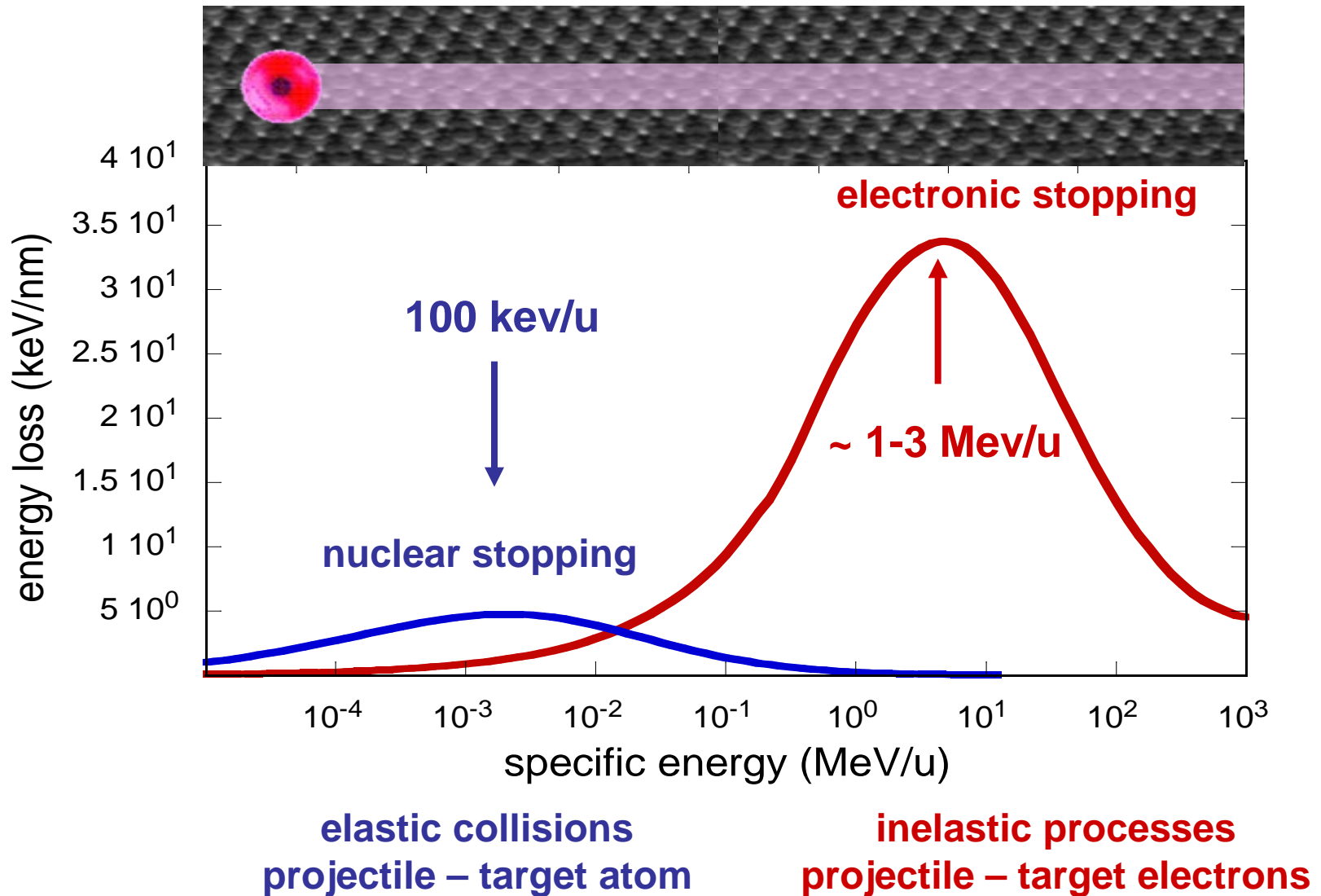
nuclear stopping



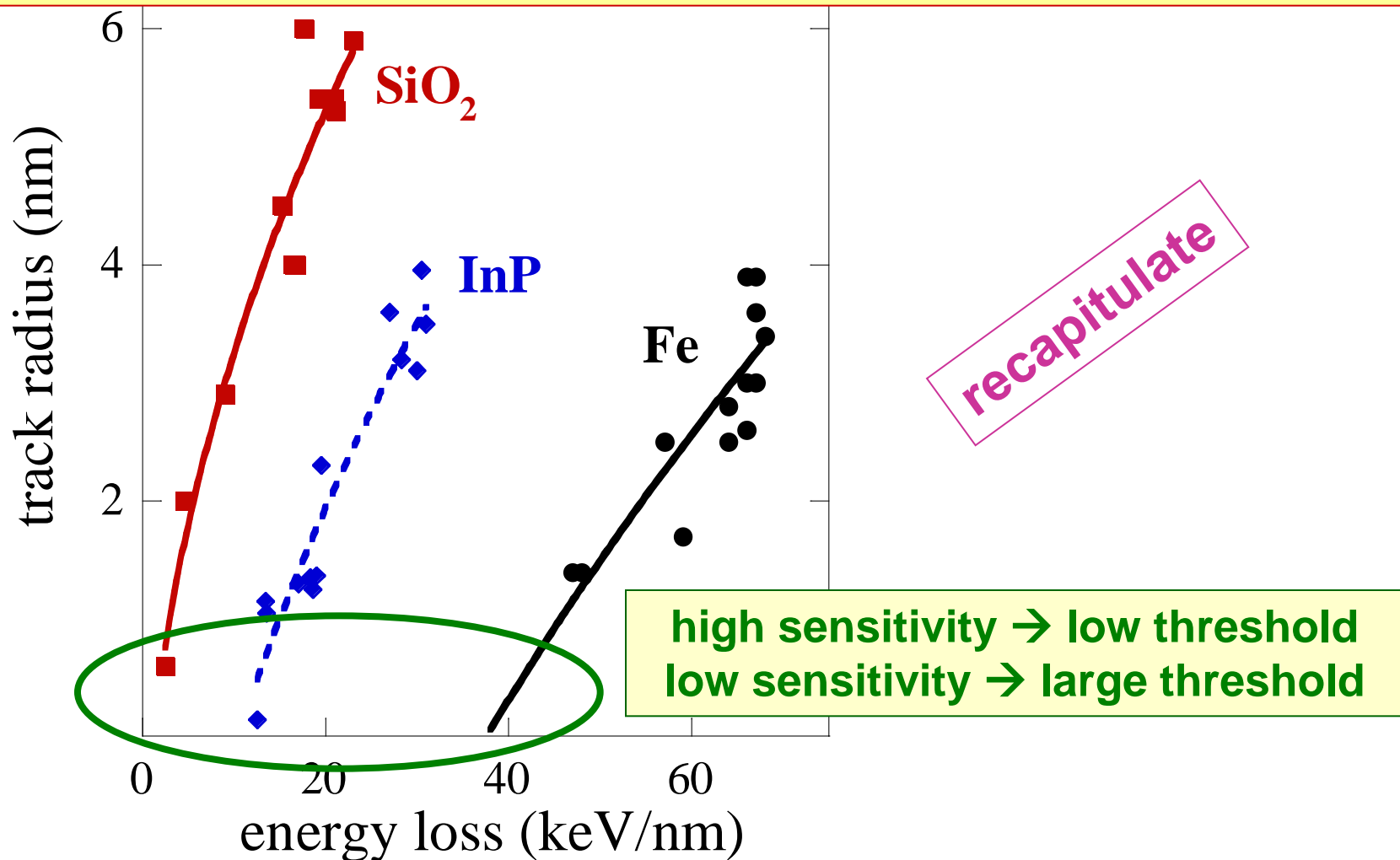
energy transfer from **electronic** to **atomic** system
→ material sensitivity

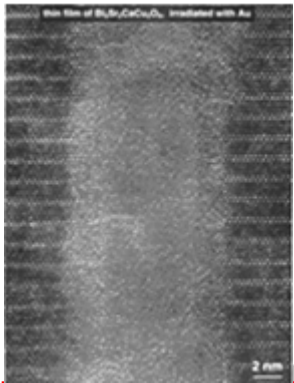
Warning: **dpa** is no helpful parameter for damage creation with MeV-GeV ions!!

Nuclear and electronic energy loss



- 1) Track size increases with electronic stopping power
- 2) Track size insulators > semiconductors > metals
- 3) Materials sensitivity scales with dE/dx threshold





Track formation depends on materials nature

high sensitivity

low sensitivity

dE/dx
threshold ~1 keV/nm

~20 keV/nm

~50 keV/nm

insulators

- polymers
- oxides, spinels
- ionic crystals
- ~~diamond~~

semi-conductors

- amorphous Si, Ge
- GeS, InP, Si_{1-x}Ge_x
- ~~Si, Ge~~

metals

- amorphous alloys
- Fe, Bi, Ti, Co, Zr
- ~~Au, Cu, Ag,~~

~~no tracks~~

Track formation in metals

metals are rather insensitive due to

- large number of conduction electrons
- very mobile electrons
- large thermal conductivity

no tracks:

**Nb, Cu, Ni, Nb,
Pd, W, Ag, Pt,
Au**

tracks:

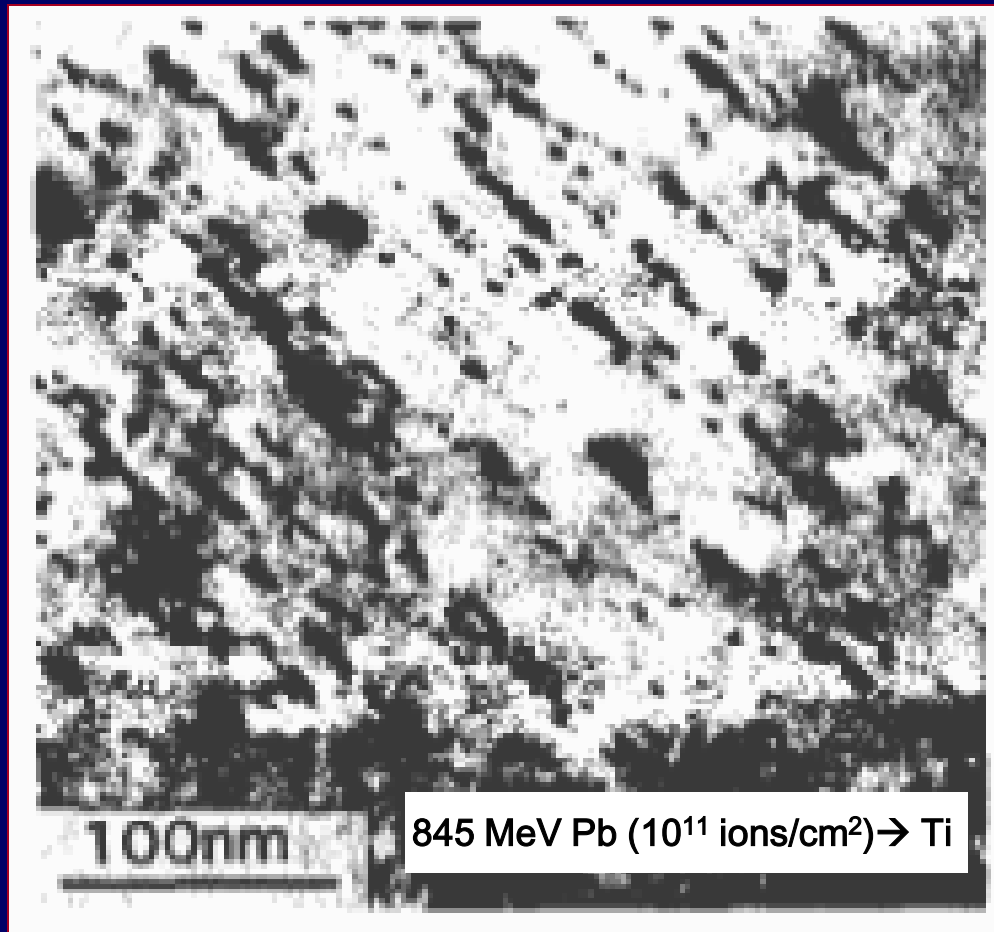
**pure metals: Fe, Ti, Co, Zr, Bi
compounds: NiB, FeCrNi, TiNi, etc
metallic glasses: PdSi, FeB, etc**

**track observation in metals rather difficult
(no amorphisation, no optical defects,...)**



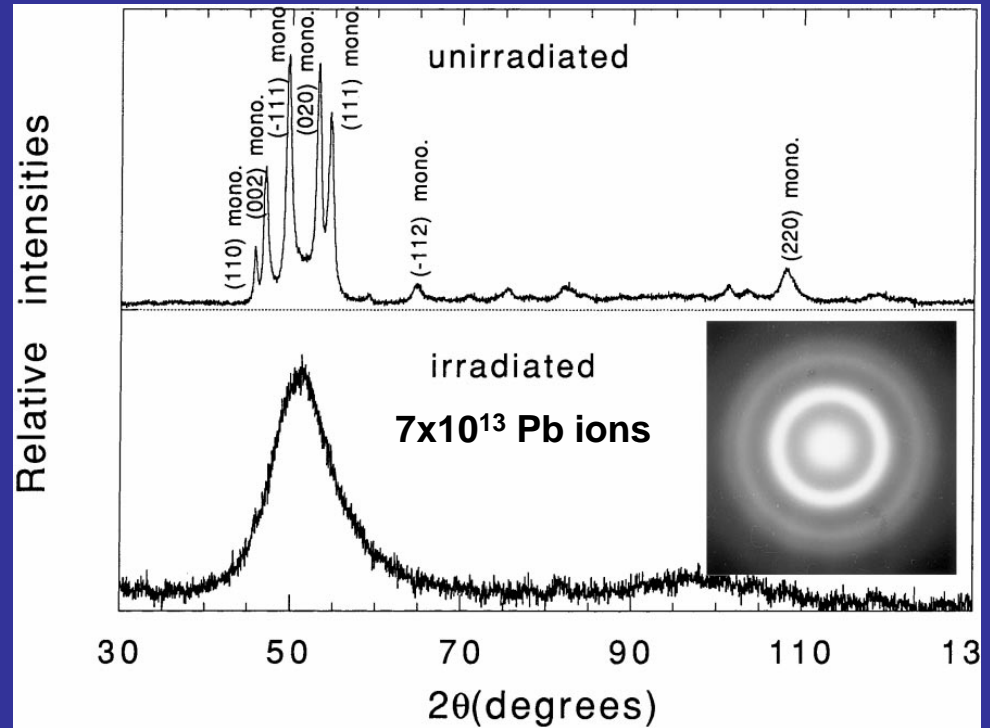
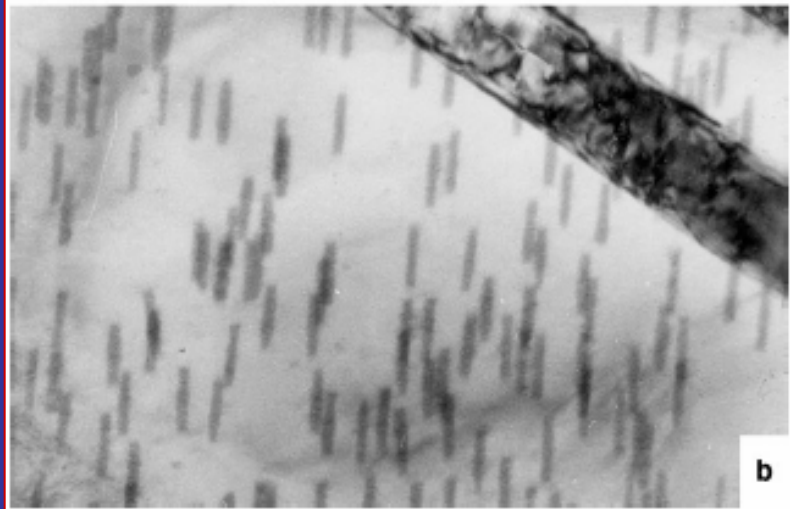
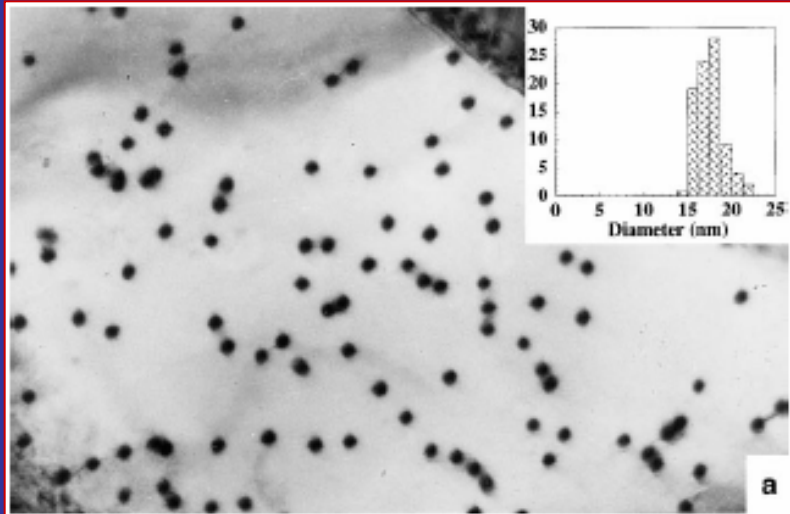
Tracks in metals (Ti)

transmission electron microscopy



dotted tracks in Ti

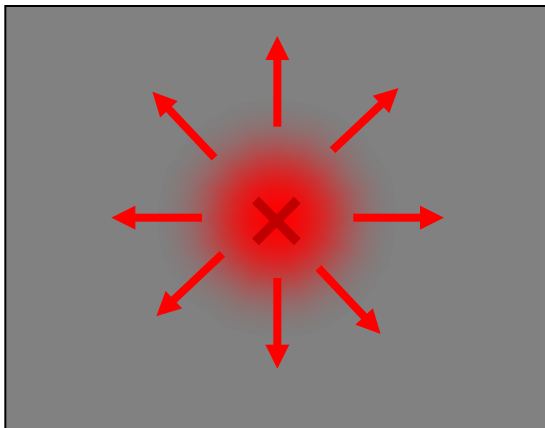
Tracks in metals (NiTi)



homogeneous cylindrical tracks
amorphization of martensitic NiTi phase
no tracks induced in austenitic phase

Thermal spike model

inelastic thermal spike or two-temperature model
sudden temperature rise in a cylinder around ion trajectory



- 1) energy diffusion within electron system
- 2) energy transfer to atoms
- 3) energy diffusion within atomic system

description in cylindrical geometry
with z-axis = ion trajectory

thermalisation in space and time!



Track formation & thermal spike model

two differential equations coupled via g

electrons

$$C_e(T_e) \frac{\partial T_e}{\partial t} = \frac{1}{r} \frac{\partial}{\partial r} \left[r K_e(T_e) \frac{\partial T_e}{\partial r} \right] - g(T_e - T_a) + A(r [\alpha_R], t)$$

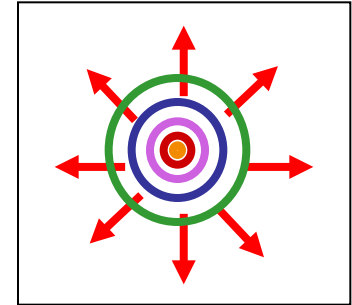
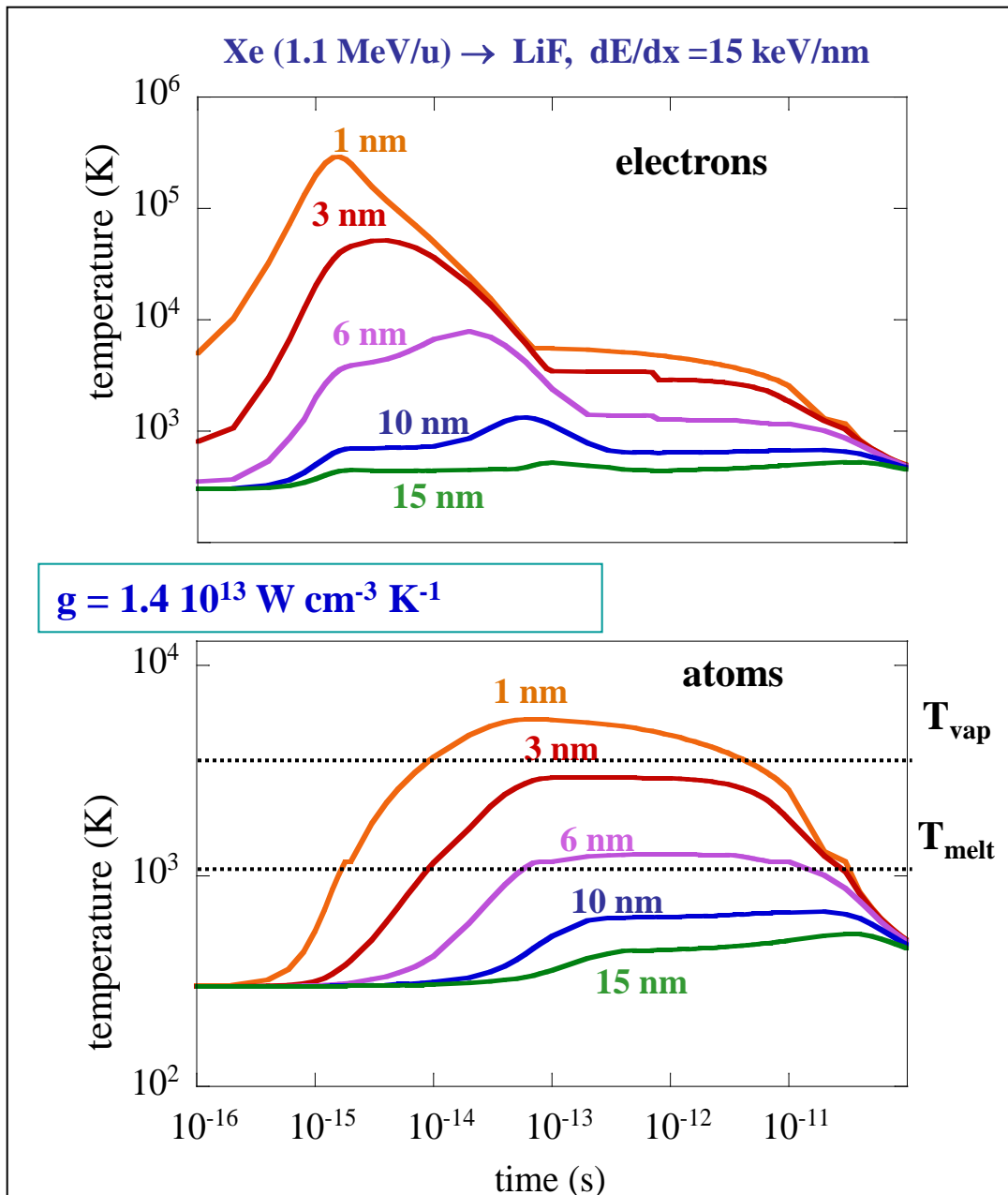
atoms

$$C_a(T_a) \frac{\partial T_a}{\partial t} = \frac{1}{r} \frac{\partial}{\partial r} \left[r K_a(T_a) \frac{\partial T_a}{\partial r} \right] + g(T_e - T_a)$$

important parameters

- specific heat $C_e(T)$ and thermal conductivity $K_e(T)$ of electron system
- specific heat $C_a(T)$ and thermal conductivity $K_a(T)$ of atomic system
- g electron phonon coupling
- latent heat

track formation \rightarrow melting depends on $C_{e,a}(T)$, $K_{e,a}(T)$, g , T_m



track formation criteria:
molten radius = track

S_e in metals under sw $\eta > 1 \rightarrow$ melting is possible 6745

Table 4. Prediction of S_e sensitivities for some selected metals. ΔH_f is the energy required to melt a metal, S_e is the maximum value that can be reached in irradiations. The r - p coupling factor is a mean value and λ is the electron mean free path. The S_e^* values are the maximum S_e values that have been used in experiments.

Metal	ΔH_f (J cm ⁻³)	S_e (TRIM91) (keV nm ⁻¹)	g ($\times 10^{11}$) (W cm ⁻³ K ⁻¹)	λ (10^{-7} cm)	η	S_e effect	Measured S_e^* effect
Be	9368	23	293	3.92	5.2	Yes	
Mg	2270	20	6.82	21.6	0.61	No	
Al	3275	28	8.14	20.9	0.63	No	No [38] $S_e^* \leq 15$ keV/nm
Ti	6701	42	92.8	6.14	5.4	Yes	Yes [22]
V	8907	52	66.4	7.56	3.3	Yes	
Cr	9075	63	94.0	6.51	5.3	Yes	
Mn	7042	63	444	2.98	32	Yes	
Fe	10977	70	49.8	8.97	2.6	Yes	Yes [13]
Co	12199	75	34.5	10.9	1.7	Yes	Yes [22]
Ni	10529	77	40.5	10.1	2.2	Yes	No [13, 17] $S_e^* \leq 67$ keV nm ⁻¹
Cu	6895	73	4.94	28.5	0.42	No	No [13] $S_e^* \leq 65$ keV nm ⁻¹
Ga	1061	46	19.6	13.1	8.1	Yes	Yes [23]
Zr	4873	48	35.0	9.55	3.5	Yes	Yes [22]
Nb	9074	63	15.0	15.2	0.97	No	No [13] $S_e^* \leq 62$ keV nm ⁻¹
Pd	7616	81	13.9	16.4	1.3	Yes?	No [17] $S_e^* \leq 75$ keV nm ⁻¹
Ag	4118	70	1.26	53.1	0.19	No	No [13, 17] $S_e^* \leq 68$ keV nm ⁻¹
Sn	1184	45	3.69	28.7	1.5	Yes	
W	14011	93	12.4	17.0	0.74	No	No [17] $S_e^* \leq 80$ keV nm ⁻¹
Pr	9003	109	10.3	18.9	1.1	No	No [13] $S_e^* \leq 96$ keV nm ⁻¹
Au	4443	99	0.91	62.5	0.18	No	
Pb	1109	55	1.56	43.3	0.85	No	
Ri	1136	50	8.20	18.4	4.2	Yes	Yes [19]
U	3149	95	12.4	16.3	3.7	Yes	

Thermal Spike calculations

experiments

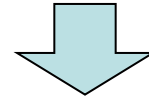
Thermal spike model

Criticism and limitations:

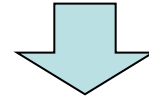
- short time scales → no equilibrium conditions
- short length scales → macroscopic material parameters
- assumes free electron diffusion for insulators
- ignores holes
- neglects recrystallization processes

Combine thermal spike model & MD calculations

thermal spike: energy deposited to electrons



electron-phonon coupling



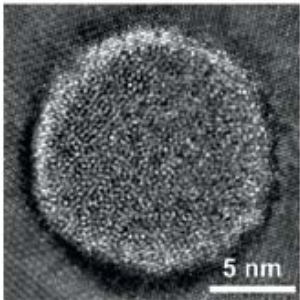
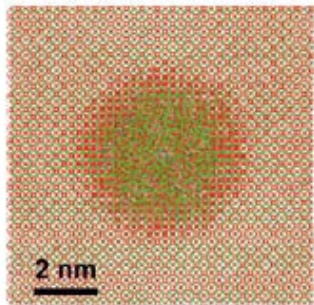
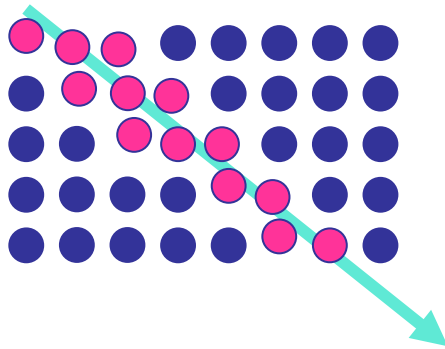
temperature profile around ion trajectory



MD: ab initio lattice calculations

solves Newton's equations of atomic motion

electron subsystem included via heat input



How to estimate radiation damage due to high-energy ion beams

- model temperature increase along ion path due to electronic stopping
- use temperature as input to MD code
- model damage creation / track formation by combining nucl & elec stopping
- simulate defect annealing processes at elevated temperature

